IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/536,037
Filing Date .....March 27, 2000
Inventor ..... Weimin (Michael) Li et al.
Assignee .....Micron Technology, Inc.
Group Art Unit 2822
Examiner .....Toniae M. Thomas
Attorney's Docket No. MI22-1398
Customer No.....021567
Title: Low k Interlevel Dielectric Layer Fabrication Methods

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

This Request for Continued Examination (RCE) Application is being filed in an abundance of caution to ensure consideration of the references listed on the attached form PTO-1449.

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether the submitted references are prior art.

Respectfully submitted,

Dated: 11 May 2005 By: James E. Lake

James E. Lake
Reg. No. 44,854

EV549570593

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-1398	SERIAL NO. 09/536,037
	LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)	APPLICANT: Li et al.	
		FILING DATE March 27, 2000	GROUP 2822

U.S. PATENT DOCUMENTS

*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,121,133	09/19/00	Iyer et al.	438	636	
	AB	6,632,712 B1	07/11/00	Ang et al.	438	212	
	AC	5,711,987	07/05/88	Bearinger et al.	427	7	
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ	TW 47112 A	01/01/2002	Taiwan – Abstract			X	
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM		Wolf, S., and Tauber, Richard, Silicon Processing for the VLSI Era; Vol. 1; Process Technology; "Silicon: Single Crystal Growth and Wafer Preparation"; pages 1 and 2
	AN		

EXAMINER	DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.